

# Note on C-DLTS application for study of radiation damage produced by short range particles

by

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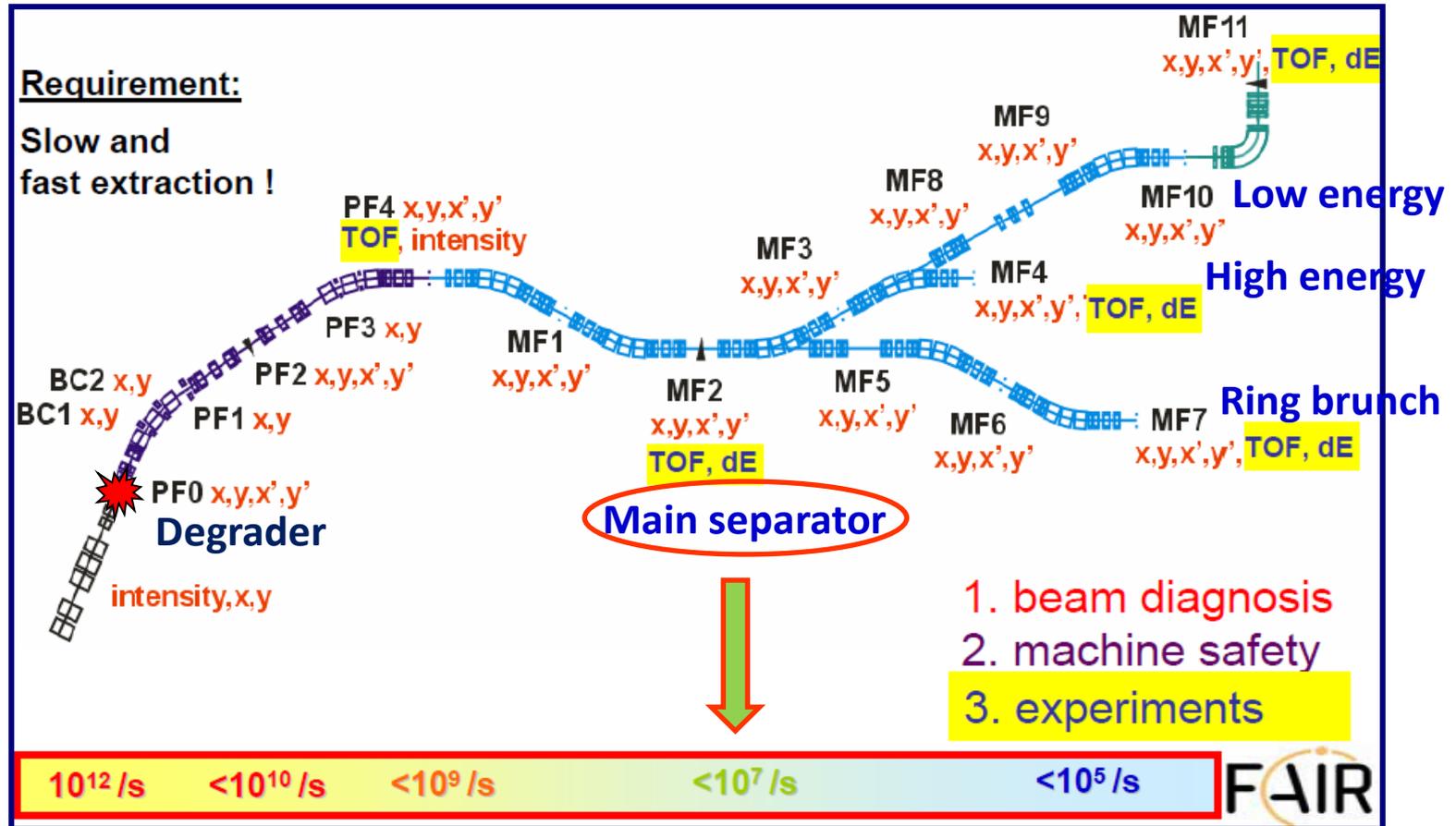
29<sup>th</sup> RD50 meeting  
CERN, 21 – 23 November, 2016

# Motivation

- **Growing interest for High-Luminosity accelerating facilities for heavy-ion physics investigations**
- **Unification and simplification of DLTS technique for the study of detector degradation**
- **Reduction of irradiation costs by using high energy heavy ions in the study of detector degradation.**

# Beam monitoring of Super-FRS

Super Fragment Separator, GSI, Darmstadt, FAIR program

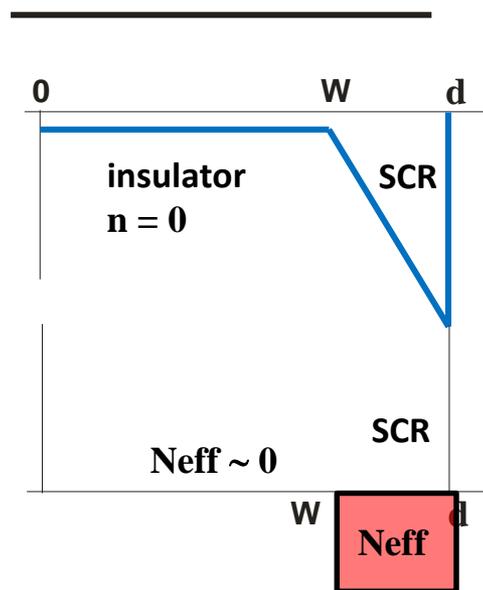
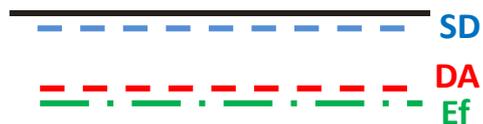


$4e13 \text{ cm}^{-2}$   
per year

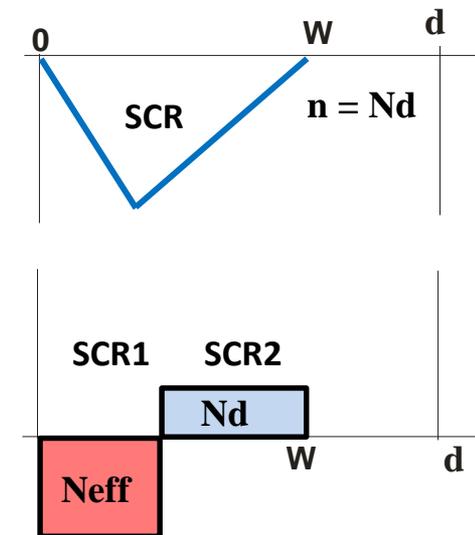
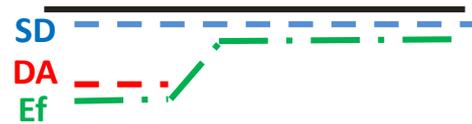
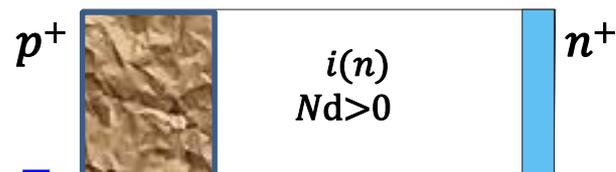
$4e11 \text{ cm}^{-2}$   
per year

# Model

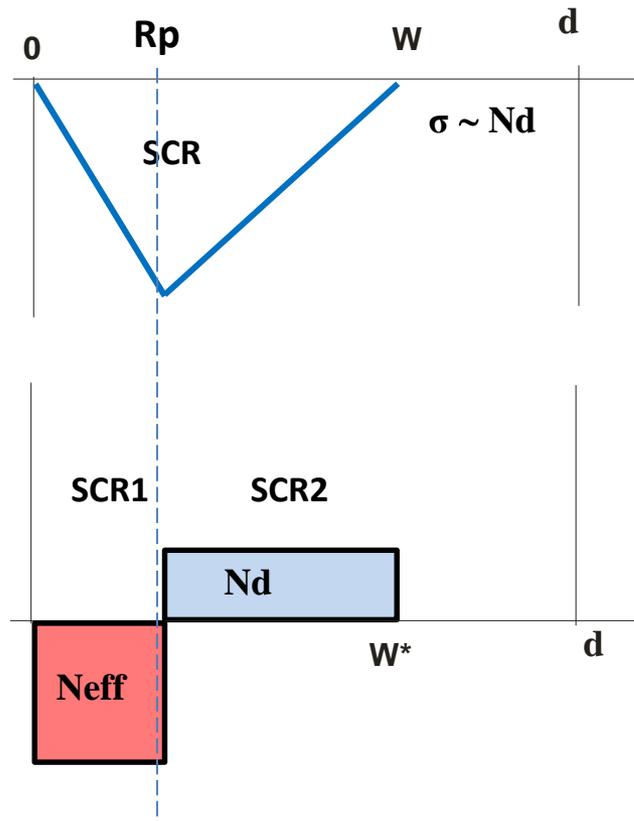
Irradiation by  
long range particles



Irradiation by  
short range particles



# Major equations



$$W^* = \sqrt{W^2 + R_p^2 \left(1 - \frac{N_{eff}}{N_d}\right)}$$

$$\frac{\Delta C}{C^*} = \left[ \frac{1}{2N_d} \times \frac{R_p}{W^*} \right] \Delta N_{DL}$$

Sensitivity of C-DLTS increases with increase of the resistivity of non irradiated region

# Samples for irradiation

## Samples:

*Si P-i-N structures*

*Epi-layers thickness = 70  $\mu\text{m}$*

*Resistivity = 1  $\text{k}\Omega\text{cm}$*

*Area = 5x5  $\text{mm}^2$*

*Vfd = 12 V*

## Irradiation:

*$^{40}\text{Ar}$*

*$E = 57\text{MeV}$*

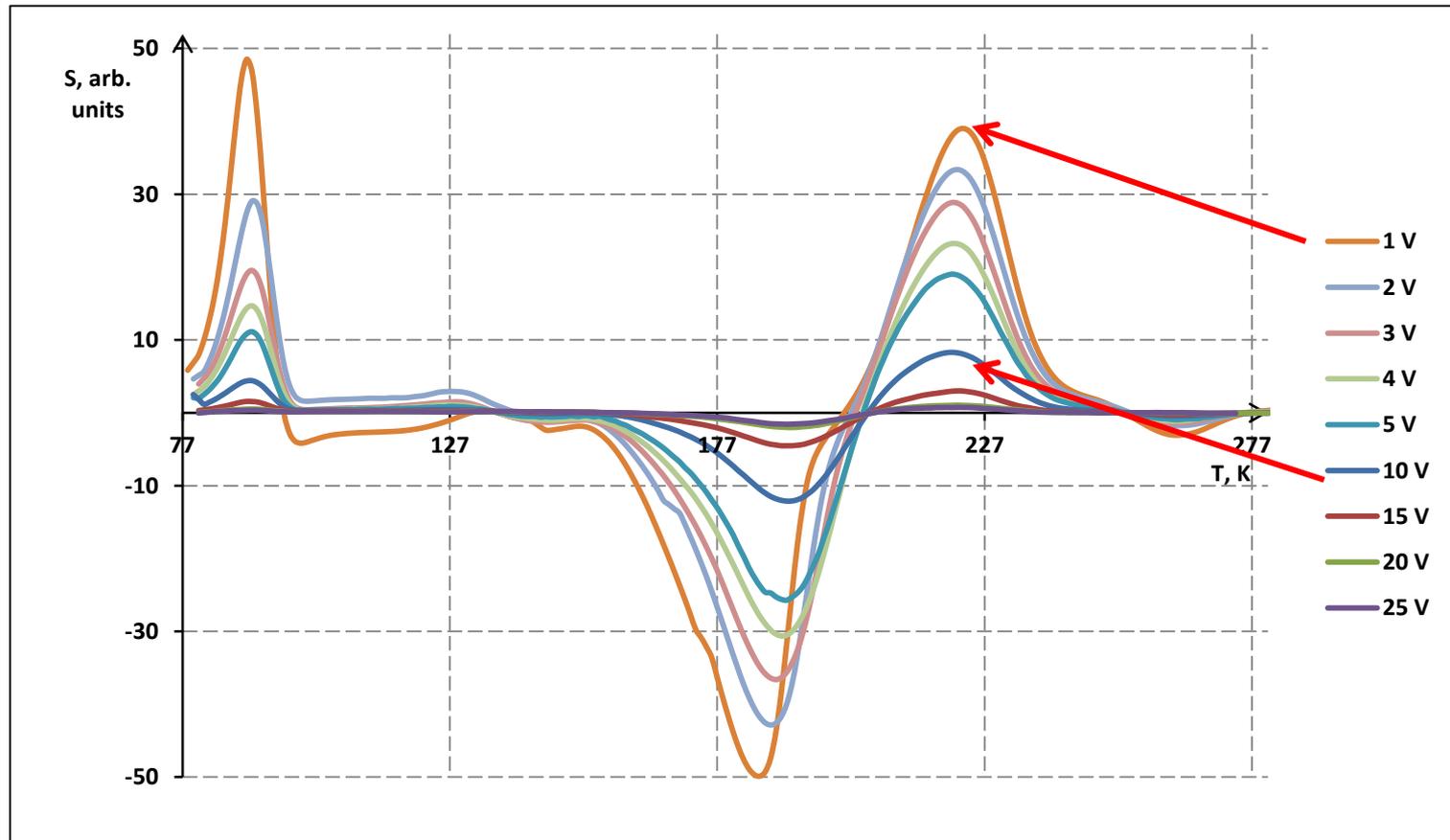
*$R_p = 14 \mu\text{m}$*

*$F1 = 3e8 \text{ cm}^{-3}$*

*$F2 = 1e10 \text{ cm}^{-3}$*

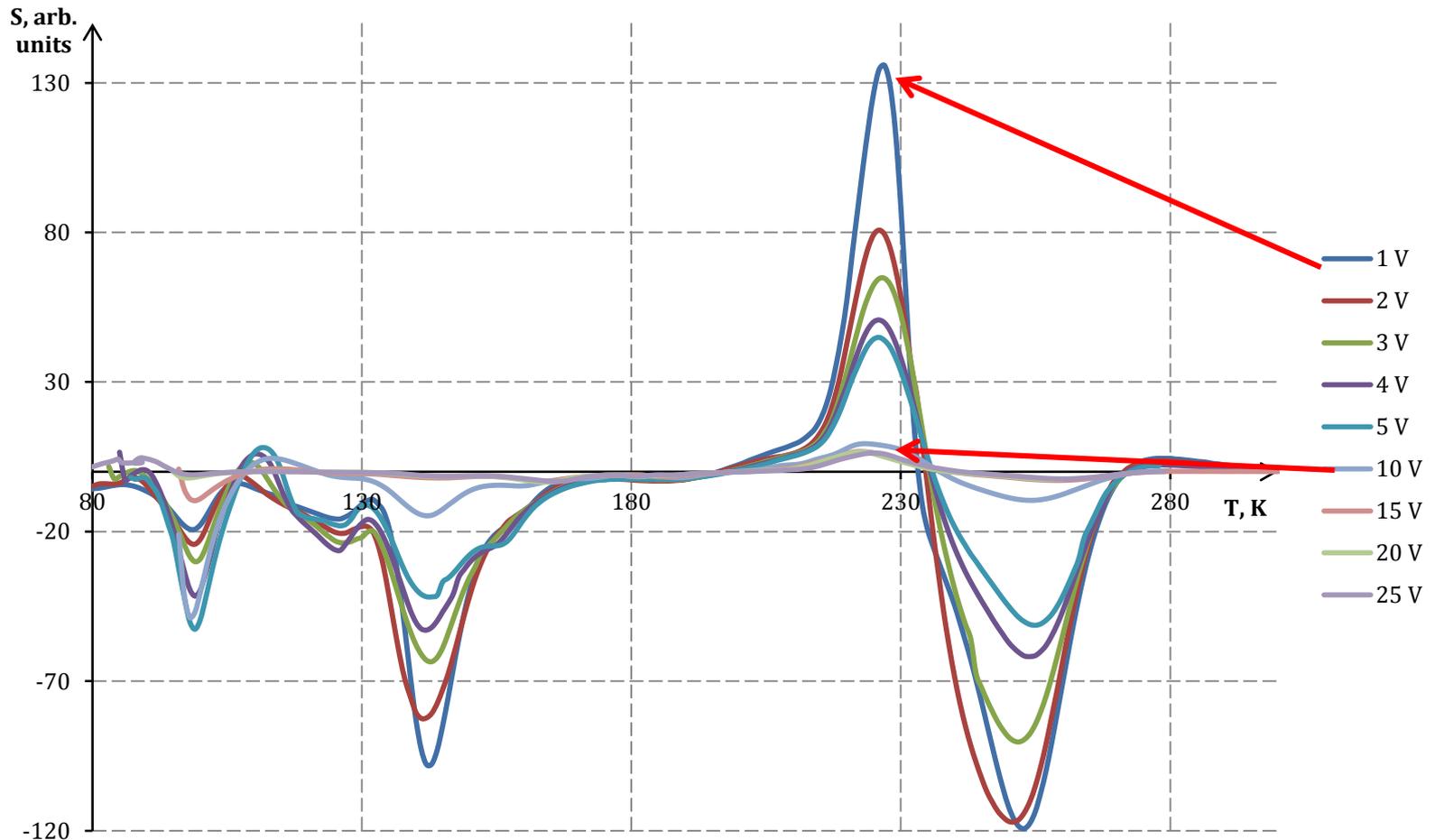
# C-DLTS spectra measured at different reverse voltage

filling current - 50 mA,  $F = 3 \cdot 10^8 \text{ cm}^{-2}$



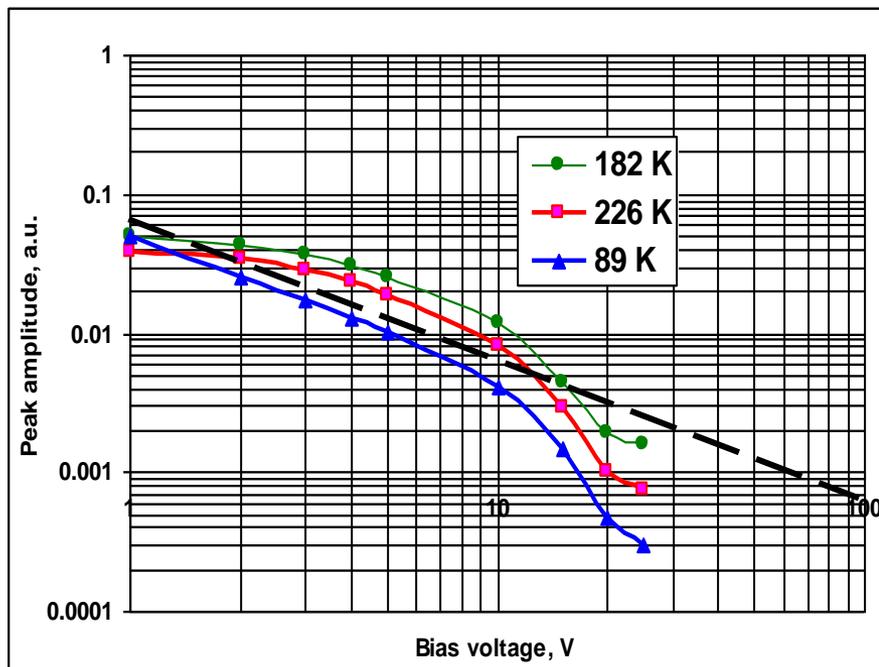
# DLTS spectra measured at different reverse voltages

filling current - 50 mA,  $F = 1 \cdot 10^{10} \text{ cm}^{-2}$

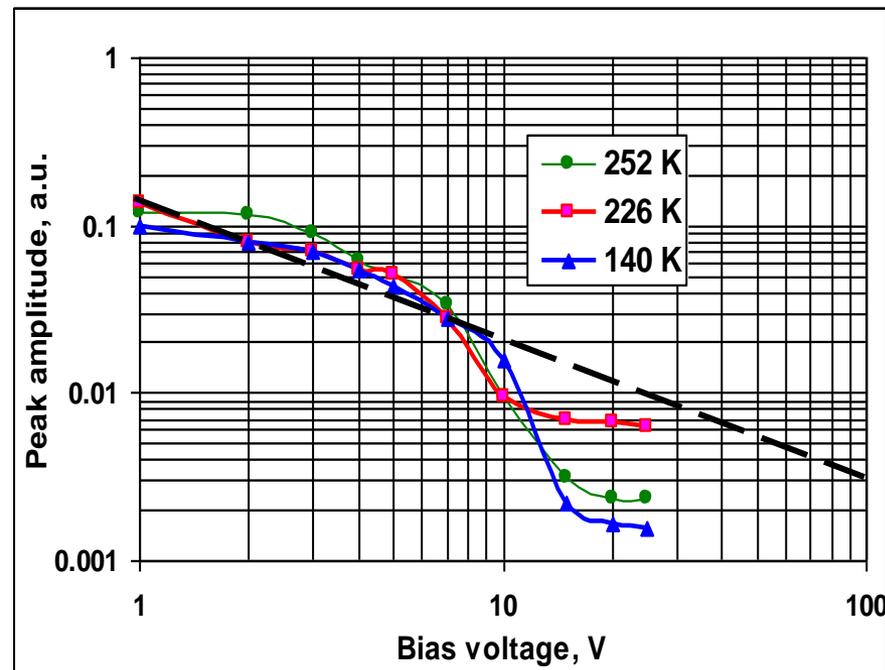


# Proof of the approach

$F = 3e8 \text{ cm}^{-2}$



$F = 1e10 \text{ cm}^{-2}$



Trend line:  $Y = X^{-0.5}$

# Conclusions

- **Standard C-DLTS allows measurement of DL spectra in overcompensated silicon diodes.**
- **The C-DLTS sensitivity depends on the resistivity of nondepleted part of the device structure and rises as the resistivity increases.**
- **The technique eliminates limitation for the C-DLTS application for overcompensated materials in diodes.**